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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/540,389	07/20/2005	Satoshi Takei	124418	2689
²⁵⁹⁴⁴ OLIFF & BERI	7590 06/07/2007 RRIDGE, PLC EXAMINER			
P.O. BOX 1992 ALEXANDRIA	28		CHOI, LING SIU	
ALEXANDRIA	A, VA 22320		ART UNIT	PAPER NUMBER
			1713	
			MAIL DATE	DELIVERY MODE
			06/07/2007	PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

		Application No.	Applicant(s)
			TAKEI ET AL.
Office Action Summary		10/540,389	
		Examiner	Art Unit
	The MAILING DATE of this communication app	Ling-Siu Choi	1713
Period f	or Reply	lears on the cover sheet with the t	correspondence address
WHIC - Exte afte - If No - Faill Any	HORTENED STATUTORY PERIOD FOR REPLY CHEVER IS LONGER, FROM THE MAILING DATE of time may be available under the provisions of 37 CFR 1.1: or SIX (6) MONTHS from the mailing date of this communication. O period for reply is specified above, the maximum statutory period of the unit or reply within the set or extended period for reply will, by statute the reply received by the Office later than three months after the mailing and patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATIO 36(a). In no event, however, may a reply be tin will apply and will expire SIX (6) MONTHS from , cause the application to become ABANDONE	N. mely filed the mailing date of this communication. ED (35 U.S.C. § 133).
Status	•		
1)⊠	Responsive to communication(s) filed on 15 M	larch_2007.	
·	·	action is non-final.	
3)[Since this application is in condition for allowar	nce except for formal matters, pr	osecution as to the merits is
	closed in accordance with the practice under E	Ex parte Quayle, 1935 C.D. 11, 4	53 O.G. 213.
Disposit	tion of Claims		
4)⊠	Claim(s) 1-12 is/are pending in the application.		
1/63	4a) Of the above claim(s) is/are withdraw	•	
5)□	Claim(s) is/are allowed.		
·	Claim(s) <u>1-12</u> is/are rejected.		
·	Claim(s) is/are objected to.		
8)[Claim(s) are subject to restriction and/o	r election requirement.	
Applicat	ion Papers		
1	The specification is objected to by the Examine	r	
-	The drawing(s) filed on <u>23 June 2005</u> is/are: a)		by the Examiner
,	Applicant may not request that any objection to the		·
	Replacement drawing sheet(s) including the correct	·	
11)[The oath or declaration is objected to by the Ex		
Priority :	under 35 U.S.C. § 119		
	Acknowledgment is made of a claim for foreign	priority under 35 H S C & 119/a)-(d) or (f)
	⊠ All b) Some * c) None of:	priority under 00 0.0.0. § 1 10(a	,-(d) 61 (1).
-,	1. Certified copies of the priority documents	s have been received.	
	2. Certified copies of the priority documents		ion No.
	3. Copies of the certified copies of the prior		
	application from the International Bureau	(PCT Rule 17.2(a)).	-
* (See the attached detailed Office action for a list	of the certified copies not receive	ed.
	•		
Attachmer	nt(s)	· .	·
· —	ce of References Cited (PTO-892)	4) Interview Summary Paper No(s)/Mail D	
_	ce of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO/SB/08)	5) Notice of Informal F	
	er No(s)/Mail Date	6) 🔲 Other:	

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DETAILED ACTION

1. This Office action is in response to the Amendment filed 03/15/2007. Claim 13 was canceled and claims 1-12 are now pending. In view of the Amendment, the objections were withdrawn and the rejections of claims 1-12 by Rutter et al. (EP 1 150 343 A2), Takei et al. (EP 1 315 045 A1), and Meador et al. (US 5,919,599) are maintained.

Claim Analysis

2. Summary of Claim 1:

A gap	A gap fill material forming composition, wherein				
	the composition is used in manufacture of semiconductor device, comprising				
	coating a photoresist on a substrate having a hole with aspect ratio shown in				
	height/diameter of 1 or more, and				
	transferring an image to the substrate by use of lithography process				
	the composition is used in a process in which the composition				
	is coated on the of substrate and is contacted with an alkaline aqueous				
	solution after baking, then the photoresist is coated				
	the composition comprises a polymer having a <u>hydroxy group or a carboxy group</u>				
	and a crosslinking agent				
	a gap fill material layer manufactured by				
	coating the gap fill material forming composition on a semiconductor				
	substrate and baking it				
	has a dissolution rate for an alkaline aqueous solution having a				
	concentration of 0.1% to 20% ranging from 3 to 200 nm per second				

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Claim Rejections - 35 USC § 102

3. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless --

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- (e) the invention was described in a patent granted on an application for patent by another filed in the United States before the invention thereof by the applicant for patent, or on an international application by another who has fulfilled the requirements of paragraphs (1), (2), and (4) of section 371(c) of this title before the invention thereof by the applicant for patent.
- 4. Claims 1-2 and 4-13 rejected under 35 U.S.C. 102(b) as being anticipated by Rutter et al. (EP 1 150 343 A2).

Rutter et al. disclose a composition comprising one or more crosslinkable polymers having a weight average molecular weight of less than or equal to about 8,000, wherein the crosslinkable polymer comprises at least one hydroxyl group containing monomer, wherein the crosslinker includes di-, tri-, tetra, or higher multifunctional ethylenically unsaturated monomer; the hydoxy group containing monomer is aliphatic or aromatic, which is vinyl phenol, vinyl cresol, vinyl methoxy phenol, hydroxyethyl (meth)acrylate, 2-hydroxypropyl (meth)acrylate, 3-hydroxypropyl (meth)acrylate, hydroxycyclohexyl (meth)acrylate, hydroxyphenyl (met)acrylate, diethyleneglycol (meth)acrylate....hydroxyethyl itaconate ([0027]; [0043]; claim 1). Rutter et al. further disclose that the composition comprises acid catalyst which includes free acid and acid generator. Rutter et al. furthermore disclose the composition provides

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substantially planarized surface in the manufacture of electronic devices and can function as an antireflective coating for 193 nm radiation when the composition contains aromatic group(abstract; [0062]). Thus, the present claims are anticipated by the disclosure of Rutter et al.

5. Claims 1-13 are rejected under 35 U.S.C. 102(e) as being anticipated by Takei et al. (EP 1 315 045 A1).

Takei et al. disclose a composition for forming a gap-filling material to be used in a semiconductor device by a method of applying the composition to the substrate with holes having an aspect ratio of at least 1 to planarize the surface of the substrate; then applying a resist coating onto a substrate; and finally transferring an image on the substrate using a lithographic process, wherein the composition comprises a polymer having a weight average molecular weight of 500 to 30,000, a crosslinking agent, and additives (page 3, lines 55-56; [0066]-[0069]; claims 1 and 17). Takei et al. further disclose that the polymer is poly(p-vinylphenol), poly(styrene-co-p-vinylphenol), poly(methyl methacrylate-co-p-vinylphenol), poly(2-hydroxyethyl methacrylate-co-p-vinylphenol), poly(butyl acrylate-co-p-vinylphenol), or novolac type phenol resin (Example 6; claims 11 and 13-16). Thus, the present claims are anticipated by the disclosure of Takei et al.

6. Claims 1-2 and 4-13 are rejected under 35 U.S.C. 102(e) as being anticipated by Meador et al. (US 5,919,599).

Meador et al. disclose a deep ultraviolet antireflective composition comprising (A) the reaction product of an acrylic polymer or copolymer and a deep ultraviolet light absorbing carboxylic acid or phenolic dye to produce a polymer or copolymer linked to the carboxylic acid or phenolic dye via a hydroxyester moiety or a hydroxyether moiety respectively, (B) a crosslinking agent, and (C) an acid catalyst (Fig. 1; claim 1). Thus, the present claims are anticipated by the disclosure of Meador et al.

Response to the Applicants' Arguments

7. Applicant's arguments filed on March 15, 2007 have been fully considered but they are not persuasive.

"EP '045 teaches a gap filling material forming composition containing a hydroxy styrene polymer and a crosslinking agent. The gap filling material is <u>subjected to dry</u> etching by use of a recessed pattern formed by resist coating on the gap filling material.

It is not used in an etching process by an alkaline aqueous solution, as is positively recited, among other features, in independent claim 1. Further, the coated film in EP '045 has a low solubility in alkaline aqueous solution due to the presence of hydroxy styrene polymer and is therefore not suitable to process such as is positively recited in independent claim 1."

Attention is drawn to claim 8 of the present invention, wherein "[t]he gap fill material forming composition according to claim 1, wherein the polymer is a polymer containing hydroxystyrene as repeating unit." Thus, a polymer containing

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hydroxystyrene can be used in an etching process by using an alkaline aqueous solution other than in dry etch process disclosed in EP'045. Referring to the property related to the dissolution rate, all references are silent on such property. However, it is an inherent property. If the composition is substantially identical to the one claimed in the present invention, the films made from these substantially identical compositions would possess the identical property such as dissolution rate in the alkaline aqueous solution.

Conclusion '

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8. **THIS ACTION IS MADE FINAL.** Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

9. Any inquiry concerning this communication or earlier communications from the

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examiner should be directed to Ling-Siu Choi whose telephone number is 571-272-1098.

If attempt to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Wu, can be reach on 571-272-1114.

LING-SUI CHOI PRIMARY EXAMINER

May 31, 2007